

FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTORNEY DOCKET NUMBER 024808-00014	NEW PATENT APPLICATION
LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>		APPLICANT Kazunari HONMA, et al.	
		FILING DATE August 1, 2003	GROUP

**U.S. PATENT DOCUMENTS**

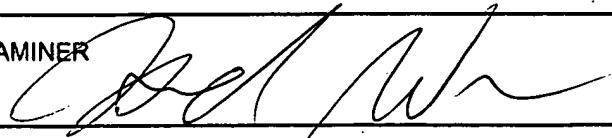
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES NO PART.
	AG	11-068057	March 9, 1999	Japan			X
	AH	2001-072416	March 21, 2001	Japan			X
	AI	11-080181	March 26, 1999	Japan			X
	AJ						
	AK						
	AL						

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

	AM	Item 1 "Low Temperature Deposition Material" Section 4 "New Deposition Material" Ferroelectric Memory Advanced Process September 13, 1999	No trans nor concs Explan provided
	AN		
	AO		

EXAMINER 	DATE CONSIDERED 6/8/05
---	---------------------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.